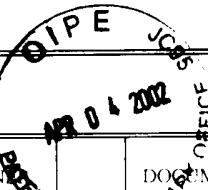


Form PTO-1449 (Modified)

Atty Docket No.:
G0131Serial No.:
10/050,417

**LIST OF PATENTS AND PUBLICATIONS
FOR APPLICANT'S
INFORMATION DISCLOSURE STATEMENT**
(Use several sheets if necessary)

Applicant: Khoi A. Phan, et al.

Filing Date:
1/16/2002 Group: Unknown

REFERENCE DESIGNATION U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER			DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AA			COPY OF PAPERS ORIGINALLY FILED					
AB			-----					
AC								
AD								
AE								
AF								
AG								
AH								
AI								
AJ								

FOREIGN PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
AK								

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

TSP	AI	"Understanding the DUV Resist Development Process Using A Develop Residue Monitoring Technique". C. Pike and J. Erhardt. Presented at Interface 1999: Microlithography Symposium, November 14-16, 1999.
TSP	AM	"An Investigation of Circular Resist Residue Defects in the Development of a 0.16μm Flash Process". J. Erhardt, K. Phan, and J. Cheng.
EXAMINER	J. R. -gj	DATE CONSIDERED 6/19/03

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.